

<b>Notice of References Cited</b>		Application/Control No.	Applicant(s)/Patent Under Reexamination SCHEUER ET AL.	
		10/050,743	Examiner	Art Unit 2881
		Zia R. Hashmi		Page 1 of 1

**U.S. PATENT DOCUMENTS**

*	Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
A	US-5,883,017	03-1999	Tepman et al.	438/800
B	US-6,528,804	03-2003	Sullivan et al.	250/492.21
C	US-			
D	US-			
E	US-			
F	US-			
G	US-			
H	US-			
I	US-			
J	US-			
K	US-			
L	US-			
M	US-			

**FOREIGN PATENT DOCUMENTS**

*	Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
N					
O					
P					
Q					
R					
S					
T					

**NON-PATENT DOCUMENTS**

*	Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)		
U	Chu et al., " Apparatus and Method for Direct Current Plasma Immersion Ion Implantation ", Pub. No. US 2001/0046566 A1,□□publication date: November 29, 2001.		
V			
W			
X			

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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